



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Florence Eschbach et al. Art Unit: Unknown  
Serial No.: 10/649,354 Examiner: Unknown  
Filed : August 26, 2003 Assignee: Intel Corporation  
Title : ATTACHING A PELLICLE FRAME TO A RETICLE

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicants call attention to the attached Information Disclosure Statement and documents listed on form PTO-1449.

This filing is being made before the receipt of a first Office action on the merits. No fee is required.

The documents are in the English language; hence no concise explanation is necessary per Rule 98(a)(3).

Consideration of the foregoing and enclosures plus the return of a copy of the enclosed form PTO-1449 with the Examiner's initials in the left column per MPEP 609 are earnestly solicited along with an early action on the merits.

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

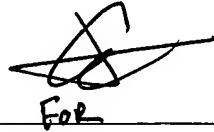
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Respectfully submitted,

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/BY  
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Substitute Form PTO-1449 (Modified)		U.S. Department of Commerce Patent and Trademark Office		Attorney's Docket No. Intel 10559-887001 / P17697		Application No. 10/649,354	
<b>Information Disclosure Statement</b> <b>by Applicant</b> (Use several sheets if necessary)				Applicant Florence Eschbach et al.			
				Filing Date August 26, 2003		Group Art Unit Unknown	
(37 CFR §1.98(b)) IDS filed 09/30/2003							
<b>U.S. Patent Documents</b>							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AI							
	AJ							
	AK							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AL	Shu et al.; "Hard Pellicle Study for 157-nm Lithography," Preprint, to appear in the Proceedings of Photomask Japan, 2002
	AM	Radiation Physics and Chemistry 62 (2001) 39-45; Oshiomu et al.; "Chemical structure and physical properties of radiation-induced crosslinking of polytetrafluoroethylene"; <a href="http://www.elsevier.com/locate/radphyschem">www.elsevier.com/locate/radphyschem</a> ; © 2001 Elsevier Science Ltd.
	AN	Reu et al.; "Mechanical analysis of hard pellicles for 157 nm lithography"; to appear in the Proceedings of the 2001 SPIE Symposium on Optical Microlithography XIV, Vol. 4346, 2001;
	AO	Kozeki et al.; "Longevity of 193nm/ArF Excimer Pellicle"; April 26, 2001; Mitsui Chemicals, Inc., Pellicles Dept.
	AP	D.W. Van Krevelen, with collaboration of P.J. Hoftyzer; "Properties of Polymers, Their Estimation and Correlation with Chemical Structure," Second, completely revised edition, pp. 68-73; Elsevier Scientific Publishing Company, Amsterdam-Oxford-New York 1976

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	